

REMARKS

Applicant would like to thank the Examiner for the careful consideration given the present application. The application has been carefully reviewed in light of the Office action, and amended as necessary to more clearly and particularly describe the subject matter which applicant regards as the invention.

Claims 1 and 4 have been amended, while new claims 6-11 have been added.

In the Office action, claims 1-6 were rejected for indefiniteness. However, the application when reviewed by the Examiner, only had five claims. Therefore, the rejections will be addressed as though only claims 1-5 were rejected.

Claims 1-5 stand rejected under 35 USC 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter. In particular, the Examiner points to the phrase "a redetermination of at least one of a panel and a substrate based on the defect information" of claims 1 and 4. Claims 1 and 4 have been amended to recite that said data management section is operable to redetermine "at least one of the defect and whether the at least one of the panel and the substrate is defective." The Examiner has also pointed to the phrase "a database for recording a defect information acquired from a liquid crystal testing device." Accordingly, claims 1 and 4 have been amended to recite a database adapted to record the defect information "which is acquired from the liquid crystal testing device, and the repair information which is acquired from the liquid crystal repair device." It is believed that these amendments remove the grounds for these rejections and notice to that effect is hereby requested.

The Examiner has rejected claims 1 and 4 under 35 U.S.C. 102(b) as being anticipated by U.S. Pat. No. 6,473,664 to Lee et al. The Examiner's rejections are traversed for the following reasons.

The present invention relates to an apparatus for managing a liquid crystal substrate. The apparatus comprising a liquid crystal testing device operable to determine whether at least one of a panel and a substrate in the liquid crystal substrate has a defect, and acquire defect information indicative of at least the defect and whether the at least one of the panel and the substrate is defective. The apparatus further comprising a liquid crystal repair device operable to repair the defect based on the defect information, and acquire repair information indicative of a defect that is actually repaired. The apparatus also includes a data management section having a database adapted to record the defect information that is acquired from the liquid crystal testing device, and the repair information which is acquired from the liquid crystal repair device. The data management section is operable to redetermine at least one of the defect and whether the at least one of the panel and the substrate is defective, based on the defect information and the repair information which are recorded in the database.

Lee involves a manufacturing process automation system for the fabrication of semiconductor devices and TFT-LCDs. Specifically, Lee discloses machines (300a, 300b, 300c, 300d) that communicate with a file server (400). Additionally, a database (110) interacts with machine servers (200a, 200b, 200c, 200d) that communicate with the machines (300a, 300b, 300c, 300d).

Amended claims 1 and 4 recite that said data management section is operable to redetermine "at least one of the defect and whether the at least one of

the panel and the substrate is defective, based on the defect information and the repair information which are recorded in said database." Review of Lee does not reveal such a data management section. Rather, in the portion of Lee cited by the Examiner, Lee discloses that the tester server connects to the file server and reads the job result data. Then the glass is relocated and reprocessed. Accordingly, it is offered that Lee does not teach redetermination of "at least one of the defect and whether the at least one of the panel and the substrate is defective, based on the defect information and the repair information which are recorded in said database." Therefore, rejection of independent claims 1 and 4 as being anticipated by Lee should be withdrawn.

The Examiner has rejected claims 2, 3, and 5 under 35 U.S.C. 103(a) as being unpatentable over U.S. Pat. No. 6,282,457 to Miura et al., in view of Lee. The Examiner's rejections are traversed for the following reasons.

Miura relates to a device for controlling a treating station. Miura teaches a coating/development unit (2) that is connected to a host computer (5) and an exposure unit (3). A transfer unit (4) transfers a wafer (W) between the coating/developing unit (2) and the exposure unit (3), and a control section (20) is incorporated in the coating/developing unit (2). The "host computer does not output recipe information for the control of the transfer system, which means that the transfer system operates independent of the host computer" (Col. 6, lines 32-35).

Miura does not correct the deficiencies of Lee. More specifically, Miura does not teach or suggest that the data management section is operable to redetermine "at least one of the defect and whether the at least one of the panel and the substrate is defective, based on the defect information and the repair information

which are recorded in said database." Therefore, even if the references were combined, they would not provide such a data management system. Thus, the Examiner has failed to provide a *prima facie* case of obviousness of claims 1 and 4, from which claims 2-3 and 5 depend. Therefore, the rejection of claims 2-3 and 5 must be withdrawn.

New claims 6-11 have been added. It is offered that new claims 6-11 contain independently patentable subject matter. Favorable consideration of claims 6-11 is hereby requested.

In light of the foregoing, it is respectfully submitted that the present application is in a condition for allowance and notice to that effect is hereby requested. If it is determined that the application is not in a condition for allowance, the Examiner is invited to initiate a telephone interview with the undersigned attorney to expedite prosecution of the present application.

If there are any additional fees resulting from this communication, please charge same to our Deposit Account No. 18-0160, our Order No. NGB-15369.

Respectfully submitted,

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